

Serial No. 10/523,844
67222-001**REMARKS**

Claims 7 and 8 are duplicates. Claims 1 and 6 have been amended to include the features of claims 7 and 8. Claims 7 and 8 have been cancelled.

Claims 1-6 are rejected under 35 U.S.C. 102(e) as being anticipated by Engdahl et al. (2001/0039168). Engdahl et al. does not disclose a wafer rotating device and a wafer including a top surface and a bottom surface that is rotated without any contact on the top surface and the bottom surface as claimed. Engdahl et al. discloses semiconductor wafers each held by a different head assembly 52 when proceeding along a process path defined by an index plate. Each head assembly 52 (shown in Figures 6 and 7) holds one wafer. When holding a wafer, the head assembly 52 retains the wafer against the wafer receiving plate 54 within the boundary defined by a retaining ring 56 that surrounds, and extends beyond, the plane of the wafer receiving plate 54 (Figure 6). A plurality of perforations, or fluid conduits 58, are distributed around the wafer receiving plate 54. *The fluid conduits 58 assist the head assembly 52 in retaining the wafer either through surface tension or a partial vacuum created between the wafer and receiving plate 54* (paragraph 53). Therefore, the wafer receiving plate 54 contacts either the top or the bottom of the wafer during processing (Figures 6 and 7). The claimed invention is not anticipated, and Applicant respectfully requests that the rejection be withdrawn.

As described in "BACKGROUND OF THE ART" and "DISCLOSURE OF THE INVENTION" of the specification, an object of the present invention is to provide a wafer rotating device that enables silicon wafers to be rotated without contacting the top and bottom of the silicon wafer and an edge flaw inspection device including the wafer rotating device. To achieve this object, the wafer rotating device and the edge flaw inspection device include "at least three rollers," "a rotation drive," "an interval adjustment mechanism," and "a load control device" which control the load applied from the rollers to the wafer in the radial direction. Therefore, the wafer is rotated and driven due to a frictional force proportional to a contact load between the cylindrical surfaces of the rollers and the wafer. At this time, the wafer is held stable in position by balancing gravity and frictional force at a position in the direction of height of any of cylindrical surfaces. The wafer can be rotated without contacting the top and bottom surfaces of the wafer (see page 6, lines 1-9, and page 9, lines 12-19 of the specification).

Additionally, the claimed invention is not anticipated because at least three rollers, a rotation drive, an interval adjustment mechanism, and a load control device of claims 1 and 6 are

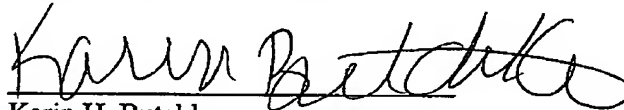
Serial No. 10/523,844
67222-001

not disclosed or suggested by Engdhal et al. The Examiner states that these components are disclosed in Figure 2 of Engdhal et al. However, these statements by the Examiner are not persuasive because the Examiner has not provided evidence as to how the components of Figure 2 of Engdhal et al. correspond to the components of claims 1 and 6.

Thus, claims 1-6 are in condition for allowance. The Commissioner is authorized to charge Deposit Account No. 50-1482, in the name of Carlson, Gaskey & Olds, P.C. \$60.00 for the one month extension fee. No additional fees are seen to be required. If any additional fees are due, however, the Commissioner is authorized to charge Deposit Account No. 50-1482, in the name of Carlson, Gaskey & Olds, P.C., for any additional fees or credit the account for any overpayment. Therefore, favorable reconsideration and allowance of this application is respectfully requested.

Respectfully Submitted,

CARLSON, GASKEY & OLDS, P.C.

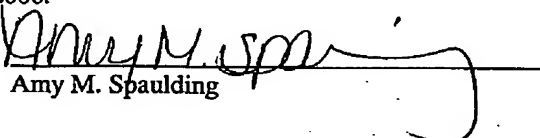


Karin H. Butchko
Registration No. 45,864
400 West Maple Road, Suite 350
Birmingham, Michigan 48009
Telephone: (248) 988-8360
Facsimile: (248) 988-8363

Dated: August 16, 2006

CERTIFICATE OF FACSIMILE

I hereby certify that this response is being facsimile transmitted to the United States Patent and Trademark Office, 571-273-8300 on August 16, 2006.


Amy M. Spaulding